Patent number Tokko No.53-46675 “Manufacturing method of Hall Element"

[Claim]

A method for manufacturing Hall element consisting of the following steps:

a step of forming a thin film by vapor deposition on a substrate having a smooth surface; a step of adhering a first magnetic material to an upper surface of the thin film; a step of mechanically peeling the magnetic material from a structure obtained by above steps; a step of removing the vapor-deposited thin film exposed by the peeling of the substrate, leaving only the parts to become a magnetic sensing part and an electrode part, and a step of forming an electrode by covering the conductive layer on upper surface of the part to become an electrode; a step of adhering a second magnetic material to cover the entire magnetic sensing part and a part of the electrode; and a step of dicing the magnetic material wafer obtained by the step into individual Hall element pieces.